

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Yoshinori IINO

SERIAL NUMBER: 10/567,665

GROUP: 3742

FILED: February 9, 2006

EXAMINER: PASCHALL, MARK H.

FOR: PLASMA PROCESSING DEVICE AND ASHING METHOD

**COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE**

COMMISSIONER FOR PATENTS  
P.O. BOX 1450  
ALEXANDRIA, VA 22313-1450

SIR:

Applicant acknowledges with appreciation the indication of Allowability of the claimed invention. In response to the Examiner's Statement of Reasons for Allowance in the Notice of Allowance of October 8, 2008, Applicant respectfully submits the following comments.

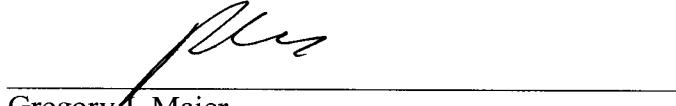
In the Examiner's Statement of Reasons for Allowance on page 2 of the Notice of Allowance mailed October 8, 2008, second paragraph states in part:

The following is an examiner's statement of reasons for allowance: the prior art of record does not each [*sic*] the claimed plasma system having a chamber, gas introduction elements, and transfer pipe as per claims 1, 3 and 5, such system inclusive of a light shield in contact with the inner wall of the chamber at an active species introduction portion into the chamber.

The above comment does not appear to be accurate with respect to independent Claims 1, 3 and 5. For example, Claims 1, 3 and 5 recite “a gas introduction mechanism” and not “gas introduction elements.” Accordingly, it is respectfully submitted that the above quoted statement does not apply to independent Claims 1, 3 and 5 (and claims dependent therefrom).

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



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Gregory J. Maier

Registration No. 25,599

Customer Number

22850

Tel. (703) 413-3000  
Fax. (703) 413-2220  
(OSMMN 05/04)

**BRADLEY D. LYtle  
REGISTRATION NO. 40,073**